		Dual beam FIB Helios 5 UX DualBeam (ThermoFisher Scientific)	Triple Beam FIB MI4000L (Hitachi High Technologies)	Dual beam FIB Quanta 3D 200i (ThermoFisher Scientific)
SEM	Gun	Monocromated Schottky Emission	Schottky Emission	Thermionic Emittion (W)
	Acceleration Voltage	0.35 kV - 30 kV	0.1 kV - 30 kV	0.5 kV - 30 kV
	Detectors	Through Lens SE/BSE Detector (TLD)	In-column SE Detector	Everhart-Thornley SE Detector (ETD)
		In-Column SE/BSE Detector (ICD)	Chamber SE Detector	-
		Mirror Detector BSE (MD)	In-column BSE Detector	-
		Everhart-Thornley SE Detector (ETD)	STEM Detector	-
		In-Chamber Secondary Electron & Ion Detector (ICE)	-	-
		Directional BSE Detector (CBS/ABS)	-	-
FIB	Ion Source	Ga LMIS	Ga LMIS	Ga LMIS
	Acc. Voltage	0.5 - 30 kV	1 kV - 30 kV	2 kV - 30 kV
	Max. Probe Current	65 nA	90 nA	65 nA
FIB-SEM Geometry		V-shape (52 deg)	L-shape Orthogonally arranged (90 deg)	V-shape (52 deg)
WD		4 mm	2 mm	15 mm
GIS		Platinum, Tungsten, Carbon	Tungsten, Carbon	Tungsten, Carbon
Max Sample Size		150 mm in diameter, 55 mm in height	4 x 4 x 2 mm	100 x 50 x 50 mm
in-situ Lift-out		EasyLift	Kleindiek	Omni Probe
Low-energy broad ion milling		-	Ar	-
Automation	TEM sample prep.	AutoTEM 5	-	-
	Serial Sectioning	Auto Slice & View 5	Cut & See	-
	Montage Imaging	MAPS 3	-	-
	Python Scripting	AutoScript 4	-	-
Analysis	XEDS	-	Oxford X-Max^{N} 150mm^{2} XEDS	-
	EBSD	Oxford Symmetry S3	-	-
Cryo Stage		Thermo Scientific CryoMAT	Hitachi SideEntry CryoHolder	Quorum Technologies PolarPrep 2000
Air-Free Transfer		○	○	○
Plasma Cleaning		○	○	-